

EV550717305



Inventor: **Brian E. Cron**

Title: **Methods for Conditioning Surfaces of Polishing Pads After
Chemical-Mechanical Polishing**

Assignee: **Micron Technology, Inc.**

Serial No.: **10/705,371**

Filed: **November 10, 2003 [RCE Filed Herewith]**

INFORMATION DISCLOSURE STATEMENT

PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98

The attached Form PTO-1449 is submitted in compliance with 37 CFR §1.56. Pursuant to FEDERAL REGISTER, Vol. 69, No. 182, pg. 56542 (September 21, 2004), no copies of any cited U.S. patents or U.S. published applications are included herewith. No admission is made regarding whether the listed reference is prior art.

Citation of this reference is respectfully requested.

Respectfully submitted,

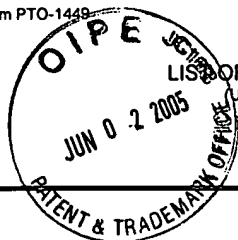
Date: 6/2/05

Attorney:

David G. Latwesen, Ph.D.
Reg. No. 38,533
Wells St. John P.S.

EV550717305

Form PTO-1449

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
MI22-2430SERIAL NO.
10/705,371LIST OF ART CITED BY APPLICANT
(Use several sheets if necessary)APPLICANT
Brian E. CronFILING DATE
Nov. 10, 2003 [RCE filed herewith]GROUP
3723

U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,332,835 B1	12/01	Nishimura et al.			
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM							
	AN							
	AO							
	AP							
	AQ							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AR		
	AS		
	AT		
EXAMINER		DATE CONSIDERED	

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.